# PVD Equipment Series

## Features

ORIGIN’s PVD equipment series is a precision PVD optical multilayer thin film vacuum deposition equipment.
This equipment is applicable in various research and experimentation fields, including thin film deposition,
optical lens production, filter production, window production, semiconductor production,
advanced material development, material synthesis, material isolation, ion cleaning,ion-assisted deposition,
vacuum electron beam welding, and more.
Furthermore, this equipment is designed with the latest technology to achieve high productivity and product quality improvement.
It consists of a vacuum chamber, vacuum pump, cooling device, electrical control, pneumatic control,
vacuum pressure control, deposition film thickness control, gas flow control,
E-beam Source (Including E-Gun, E-Gun power supply, Crucible, and Crucible liner), and
Ion-beam source (Including Ion-Gun and Ion-Gun power supply).

* ORIGIN’s product, PVD Equipment Series, can be custom-produced upon request.

* Some layouts may not be installable, so please inquire before placing an order.

* We cannot guarantee the product’s performance when used in combination with products from other manufacturers.

# Technical Specifications

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| Chamber inside dimensions (Unit: Ø) | 600, 750, 1200, 1500, 1600, 2000, 2050 or Option |
| EB-power supplies | ISA−7000 or Option ( Customization available for orders ) |
| Crucible | 1, 4, 8, 12, Etc pocket to 25cc or Option |
| Ion-power supplies | ISA−8000 or Option ( Customization available for orders) |
| Chamber main material & Coating jig | SUS304 & Substrate rotation system or Option |
| View port | 150 Diameter tempered glass include shutter, 1 to 3 Port or Option |
| Uniformity mask | Connector type SUS alloy |
| Vacuum measuring | “Granville-phillips” GP−307 or Option |
| Deposition controller | “Inficon” IC−6 or Option |
| Chamber inside shield | Separation type SUS alloy |
| Gas supplies | 2 to 3 MFC purity 99.9% |
| Pressure control, Coating control | Auto, Manual |
| Pressure (Approximately) | Ultimate 6.0E−7 Torr, Working 2.0E−5 Torr |
| High vacuum pump | Option |
| Booster vacuum pump | Option |
| Rotary vacuum pump | Option |
| Poly cold | Option |
| Substrate heater | Halogen heater or Option |
| Main controller | Option |
| Line power | 220Vac and 380Vac 3ph 50Hz / 60Hz ±5% Approximately 80KVA |
| Nonlinearity | ±2% FS |
| Vibration in the workspace | Approximately X,Y,Z < 0.2G Less than |
| Operating temperation & Humidity | 17 to 25℃, 20 to 70% RH |